




Sessions on Tuesday

08:00	Registration starts	
09:00 - 11:45	Tutorial Alan Weber Cimetrix by PDF Solutions	MOVIE THEATER 7
12:30 - 13:55	MOVIE THEATER 8 Conference Opening Session Session Chairs: Martin Schellenberger Jochen Kinauer	
12:30	R1 Opening Remarks	Martin Schellenberger Fraunhofer IISB Jochen Kinauer camLine GmbH
12:40	K1 Keynote:	
13:10	I1 Invited Talk: MaiMa autofrei - A digital quality gate for tool requalification after maintenance employing MaiMa and Space	Yvonne Bergmann Robert Bosch GmbH
13:55	Short break to change rooms	
14:00 - 15:00	MOVIE THEATER 8 Session 1 - Part 1 Session Chair: Bert Müller	MOVIE THEATER 7 Session 3 - Part 1 Session Chair: Thomas Müller
14:00	1.1 ICP-etching of GaN HFET structures: real time statistical process control of nm-thick GaN layers by means of end point detection Anthony Martinez LayTec AG	3.1 Industry 4.0 boosts predictive maintenance for semiconductor testers Oleg Fotteler SPEA GmbH
14:30	1.2 Enabling Higher Resolution Measurement to Support Zone Control John Mc Manus Nova Ltd	3.2 Models for Gas Flow Reduction Michael Klick Plasmetrex GmbH
15:00	Coffee Break	
15:30 - 16:30	MOVIE THEATER 8 Session 1 - Part 2 Session Chair: Bert Müller	MOVIE THEATER 7 Session 2 - Part 1 Session Chair: Thomas Müller
15:30	1.3 "antiPilo AI": First-Time-Right Lithography in a High-Mix, Low-Volume FAB using a Machine Learning boosted R2R controller Martin Schwarz X-FAB Dresden	2.1 Sensor Matching Application Concept Using Cloud Storage, Cloud Analytics and Computing Services Frank Wagenbreth GlobalFoundries
16:00	1.4 A Digital Twin of a real fab - how to create it? Torsten Thieme Deaxo GmbH	2.2 Harnessing the Power of Event Sequence Analysis for Semiconductor Smart Manufacturing Alan Weber Cimetrix by PDF Solutions
16:30	Sponsor Talks Session Chair: Martin Schellenberger	MOVIE THEATER 8
17:00	Poster & Exhibitor Presentation Session Chair: Martin Schellenberger	MOVIE THEATER 8
18:00	Poster Reception	CINEMAXX FOYER - LEVEL 2

Sessions on Wednesday - morning

08:00	Registration starts	
09:00 - 10:30	MOVIE THEATER 8 Opening & Invited Talk Session Chairs: Martin Schellenberger Jochen Kinauer	
09:00	R2	Opening Remarks Martin Schellenberger Fraunhofer IISB Jochen Kinauer camLine GmbH
09:10	I2	Invited Talk: Novel approach to master the challenges of run-to-run control in high-mix low-volume production – Part 3 Ulf Seidel Infineon Technologies Dresden
10:00	Coffee Break CINEMAXX FOYER	
10:30 - 12:30	MOVIE THEATER 8 Session 2 – Part 2 Session Chair: Christian Knöll	SESSION SPONSOR: 
10:30 - 12:30	MOVIE THEATER 7 Session 3 – Part 2 Session Chair: Ulf Seidel	SESSION SPONSOR: 
10:30	2.3 Machine-Learning-based Classification of Via Defects in SEM-Images Abdelmalek Cherchari Fraunhofer Institute of Electronic Nano Systems ENAS, Technische Universität Chemnitz	3.3 Unit process & equipment productivity shock sentinel on evg wtw bonding system robot handling Marco Cartotti STMicroelectronics & Daniele Lavalle Technofitting
11:00	2.4 Unpacking Wafer Analysis Complexity: Using Siamese Networks for a Novel Wafer Map Fingerprint Comparability Approach Christian Weber University of Siegen	3.4 New generation of equipment/host communication as an enabler for data platforms, AI and digital twin Marco Grafe Carl Zeiss Digital Innovation
11:30	2.5 R&D³: a modern data stack for imec researchers Wim Vancuyck Imec	3.5 Digitalisation & AI for Industry 5.0 Applications to Make Semiconductor Manufacturing Sustainable Germar Schneider Infineon Technologies Dresden
12:00	2.6 Quantum Computing in Semiconductor Manufacturing – Potentials and Outlook Christoph Eichhammer Fraunhofer Institute for Integrated Systems and Device Technology (IISB)	3.6 From dispatching to autonomous scheduling: a case study at a real wafer fab Semya Elaoud Flexciton Ltd.
12:30	LUNCH	SPONSORED by:  CINEMAXX FOYER

Sessions on Wednesday - afternoon

13:30 - 15:30	Young Talent Session Session Chair: Martin Schellenberger	MOVIE THEATER 8
13:30	T1 In-Wafer Etch Process Control Based on real-time PI-VM under MFC aging scenario in Ar/SF6/O2 VHF-CCP Ji-Won Kwon Seoul National University	
13:50	T2 Machine Learning Prediction Models for Generic Run-to-Run Control in High-Mix Semiconductor Industry Lucile Terras EMSE	
14:10	T3 CMP Process Modelling using Machine Learning Techniques Hossam Elwan Vishay Siliconix Itzehoe GmbH	
14:30	T4 Expertise-based optimization of yield prediction on logistic delivery grids Stefan Stroka ams OSRAM Group & LMU Munich	
14:50	T5 Optimizing Process Capability and Cycle Time through Virtual Metrology Leonard Yeo Micron Technology	
15:10	Coffee Break	CINEMAXX FOYER
15:45 - 17:15	MOVIE THEATER 8 SESSION 2 - PART 3 Session Chair: Gerd Fischer	SESSION SPONSOR:  PEERGROUP
15:45	2.7 FDC System Integration and Application for Opto Semiconductor Epitaxy Tools Thomas Bauer ams-OSRAM Group	MOVIE THEATER 7 Session 3 - Part 3 Session Chair: Robert McCafferty
15:45	3.7 A Simulation and Evaluation Platform for the Training of a Reinforcement Learning Enabled Dispatch Agent to Reduce Fab Cycle Time Peter Lendermann D-SIMLAB Technologies & Patrick Stöckermann Infineon Technologies Dresden	SESSION SPONSOR:  INFICON
16:15	2.8 Combining Physical and Virtual Metrology for Adaptive Process Control Christian Hörr ZEISS Digital Innovation	3.8 Jointly optimizing intralogistics, WIP flow and stocker management in a segregated high-automation semiconductor front-end fab Holger Brandl SYSTEMA GmbH
16:45	2.9 Yield management Equipment Performance Optimization for Yield improvement Dmitrii Fomin & Massimo Orazio Spata (by remote) STMicroelectronics	3.9 Development of a Concept for a Dynamic Dispatching Method Based on a Data-Driven Classification of Manufacturing Scenarios: Start at an Academic Level Rocky Telatko University of Applied Sciences Dresden
17:15	Break / End of Conference Day	
18:00 - 21:30	Bus Transfer / Conference Dinner	

Sessions on Thursday

08:30	Registration	
09:00 - 10:30	MOVIE THEATER 8 Opening Session Session Chairs: Martin Schellenberger Jochen Kinauer	
09:00	R3	Opening Remarks Martin Schellenberger Jochen Kinauer
09:10	K2	Keynote: Technologies in Generative AI and the Future of Coding Frank Schönefeld Telekom MMS
09:40	I3	Invited Talk: Rethinking Education and Training for nowadays semiconductor manufacturing by adapted Bauhaus Education Philosophy Sabrina Anger Fraunhofer IISB
10:30	Coffee Break	CINEMAXX FOYER
11:00 - 12:00	MOVIE THEATER 8 Session 2 - Part 4 Session Chair: Alan Weber	SESSION SPONSOR: 
11:00	210	Smart device on facilities to prevent unscheduled facilities interruption Giuseppe Fazio STMicroelectonic
11:30	211	Getting and staying ahead of the bad guys, an industry plan for cybersecurity Doug Suerich PEER Group
11:00	3.10	Process and equipment performance optimization Pietro Petruzza STMicroelectronics
11:30	3.11	AI-Enhanced Digital Twin Architecture and local dispatching methods for yield improvement in a microelectronics facility Roberto Rosario Corsini & Marco Stefano Scroppo STMicroelectronics
12:00	LUNCH	SPONSORED by: 
12:00	CINEMAXX FOYER	
13:00 - 14:30	MOVIE THEATER 8 Session 2 - Part 5 Session Chair: Alan Weber	SESSION SPONSOR: 
13:00	212	Machine Learning and Explainable AI to Manage Process Variabilities and Resource Efficiencies in Semiconductor Manufacturing Venugopal Ramadasu Vienna University of Economics and Business
13:30	213	Optimizing Yield and Process Efficiency in Semiconductor Fabs through AI Monica McDonnell teradata
13:00	3.12	Processing time and machine availability prediction using neural networks Jasper van Heugten minds.ai
13:30	3.13	Integrating Transport Loads in Production Planning: A Simulation-Driven Approach Vincent Betker TU Dresden
14:00	214	Stratified Boosting with Adaptive Online Learning for Virtual Metrology at a Massive Scale Brendon Choe Gauss Labs Inc.
14:00	3.14	AI powered solutions addressing the semiconductor labor shortage John Behnke Inficon
14:30	AWARD CEREMONY & CLOSING	MOVIE THEATRE 8
15:00	END OF CONFERENCE	